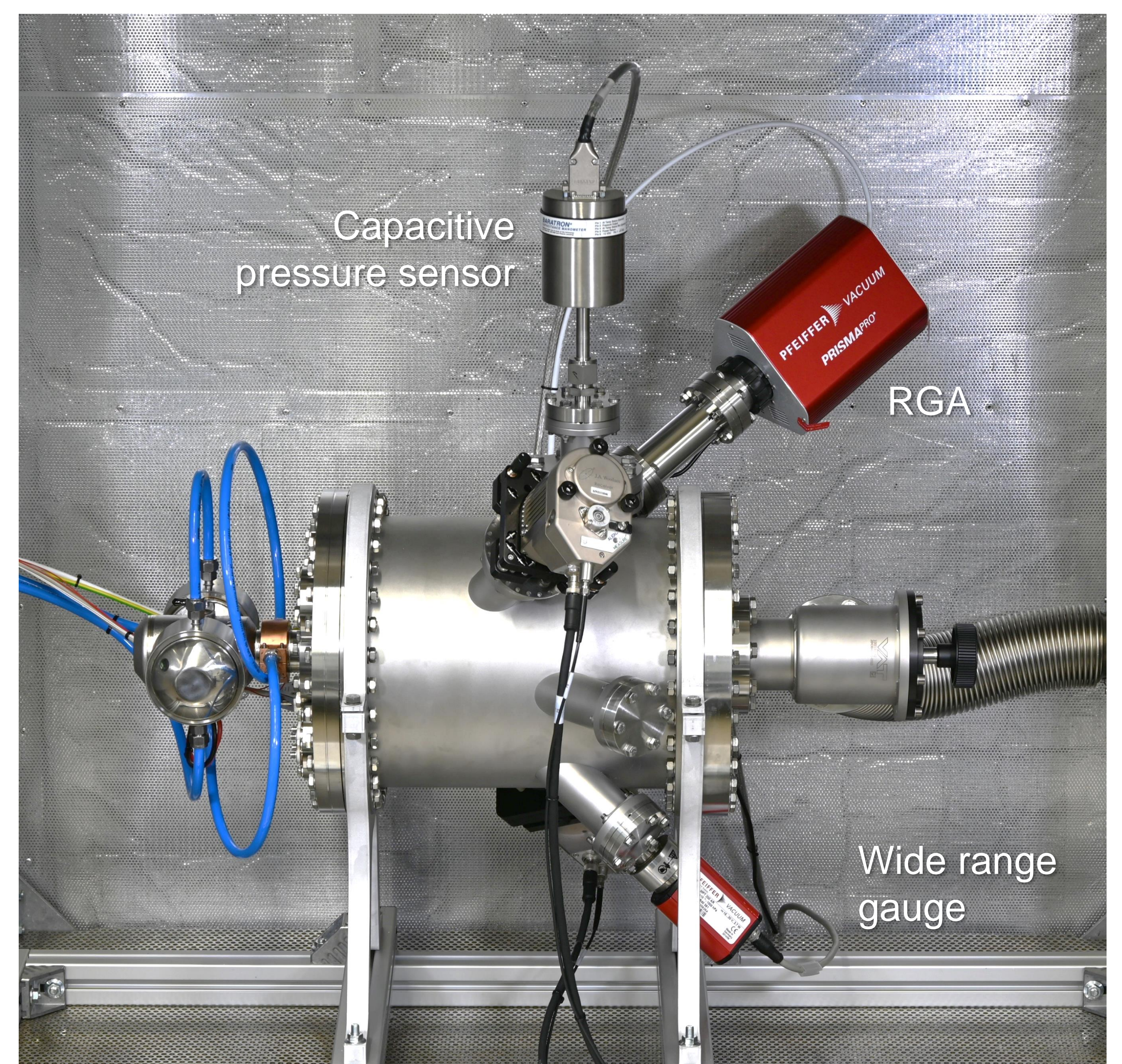


Adsorption and Desorption on Cryogenic Mirror Surfaces in Vacuum

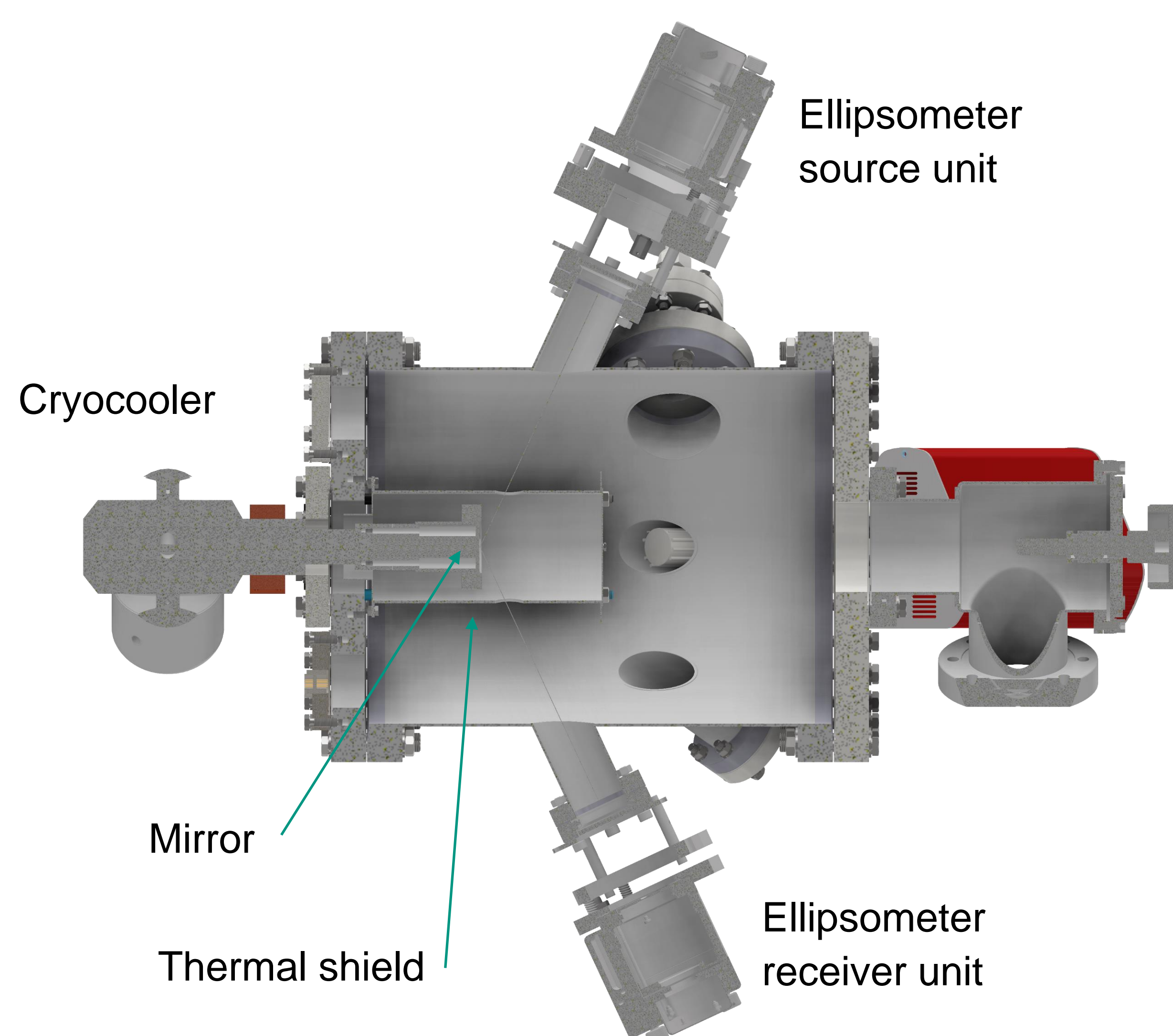
Adrian Schwenck (KIT), Freek Molkenboer (TNO), Jessica Steinlechner (MU), Joachim Wolf (KIT)

Goal

- **Controlled contamination monitoring** in vacuum on mirror surfaces cooled to cryogenic temperatures in different gas environments like water, CO₂, hydrocarbons and other.
- **Develop a versatile test facility** for adsorption / desorption monitoring and in-situ cleaning technologies in vacuum at cryogenic temperatures.
- **Investigate technologies for in-situ monitoring** of adsorption and desorption rates on surfaces:
 - **Spectroscopic ellipsometry** for the measurement of the thickness of the adsorbed layer
 - **Quartz crystal microbalances** are well established for the measurement of mass variations at room temperature and above, but come with challenges at cryogenic temperatures.
 - **Cross-calibration** of both methods
- Investigate technologies for **in-situ cleaning methods** of mirror surfaces at cryogenic temperatures (LF-TM).
 - Electron stimulated desorption (with R. Cimino et al.)
 - UV light
 - Ar plasma



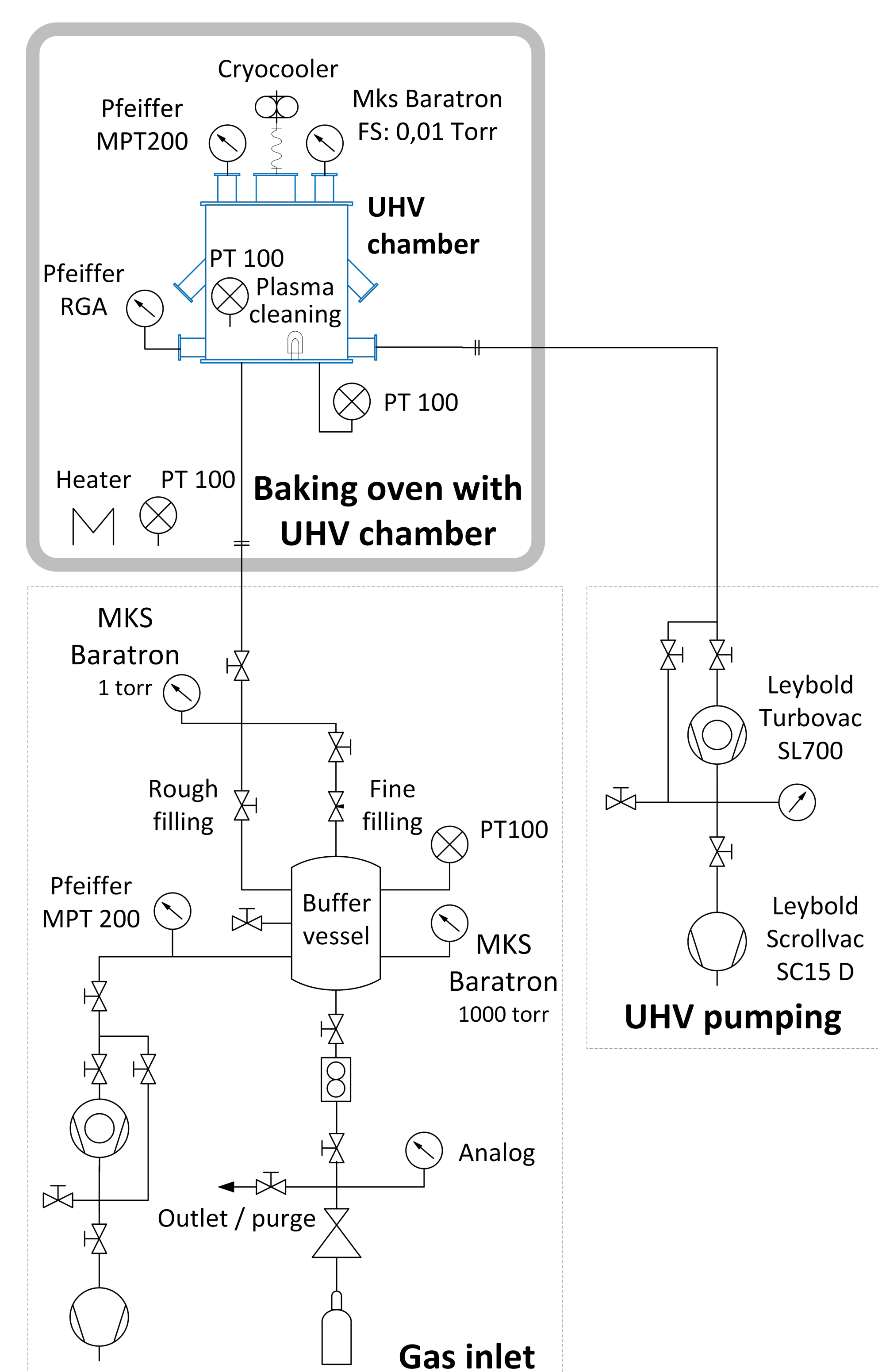
Picture of the experiment



Cross section through the plane of the ellipsometer

Equipment

- **Ellipsometer:** J.A Woollam iSE; 400nm to 1000nm
- **Cryocooler:** Lihan TC4188, water cooled, sterling type, cooling power: 2 W at 40K, 15W at 77K
- **Residual gass analyzer (RGA):** Pfeiffer Prisma Pro QMG250, measurement range: 1 – 200u
- **Mirror:** Si die from a polished 6" Si wafer
- **Capacitive pressure Sensor:** MKS Baratron, FS = 0,01 Torr
- **Wide range gauge:** Pfeiffer MPT200, measurement range: $5 \times 10^{-9} - 1000$ mbar in air, O₂, CO, N₂



Vacuum and instrumentation scheme